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## Micromachined gas sensors based on Au-functionalized SnO<sub>2</sub> nanorods directly integrated without catalyst seeds *via* AA-CVD

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### Abstract

Tin oxide nanorods functionalized with Au nanoparticles are vapour synthesised at relatively lower temperatures than previously reported and without the need of catalyst seeds using co-deposition method *via* aerosol-assisted chemical vapour deposition. These functionalized structures formed directly, in a single-step process, on silicon micromachined platforms are tested toward H<sub>2</sub>, showing 12-fold greater response, 6-fold faster response time and better selectivity to CO compared to a similar non-functionalized system. Results show the significance of these method to form highly gas sensitive nanostructures compatible with the complementary electronic for the fabrication of gas microsensor devices.

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### 1. Introduction

Tin oxide is an intrinsic n-type wide-bandgap semiconducting metal oxide with applications in transparent conducting electrodes, solar cells and gas sensors.[1, 2] In particular, tin oxide is used in most current commercial resistive gas sensors and is the most studied material in the gas sensing literature, with demonstrated sensitivity to

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carbon monoxide, hydrogen, ethanol, and nitrogen dioxide, amongst others.[2-4] Whilst tin oxide nanorods (NRs) have been synthesized (often with catalyst seeds) using various routes, including chemical vapour deposition (CVD), the formation of these structures via aerosol-assisted (AA) CVD without catalyst seeds, i.e., via vapor-solid (VS) mechanism, and their in-situ functionalization with Au nanoparticles (NPs) have not been developed before. AA-CVD works at atmospheric pressure and relies on a solution-based delivery approach, providing advantages over traditional CVD as it allows for a wider range of precursors to be utilised. It also allows for the functionalization of SMOx nanostructures with metal NPs in a single processing step *via* co-deposition, as demonstrated previously for incorporation of gold or platinum NPs segregated at the surface of tungsten oxide nanostructures.[5]

Here we report the AA-CVD of Au-functionalised and non-functionalized tin oxide NRs (Au@SnO<sub>2</sub> and SnO<sub>2</sub>, respectively) directly on silicon micromachined platforms ( $\mu$ MP) for the fabrication of chemoresistive gas sensors.

## 2. Materials and Methods

Au@SnO<sub>2</sub> and SnO<sub>2</sub> NRs were deposited directly on  $\mu$ MP at 620 °C *via* AA-CVD of a mixture of tin (IV) chloride pentahydrate (30 mg, SnCl<sub>4</sub>·5H<sub>2</sub>O, Sigma-Aldrich,  $\geq$ 98%) and tetrachloroauric acid trihydrate (4.2 mg, HAuCl<sub>4</sub>·3H<sub>2</sub>O, Sigma-Aldrich, 99.9%) dissolved in acetone (15 ml, Sigma-Aldrich,  $\geq$ 99.6%) or only tin (IV) chloride pentahydrate (30 mg, SnCl<sub>4</sub>·5H<sub>2</sub>O, Sigma-Aldrich,  $\geq$ 98%) dissolved in acetone (15 ml, Sigma-Aldrich,  $\geq$ 99.6%), respectively, using the method and system reported previously.[5] The  $\mu$ MP consisted of an array of four SiO<sub>2</sub>/Si<sub>3</sub>N<sub>4</sub>/SiO<sub>2</sub> membrane, each of them with isolated polysilicon heaters and platinum electrodes (gap: 50  $\mu$ m, thick: 0.2  $\mu$ m).[6] The sensing films were deposited on the  $\mu$ MP using a shadow mask in order to protect the contacts and subsequently bonded in a TO-8 package (inset in Fig. 1).

The morphology of the samples was examined using SEM (Tescan FE Mira II LMU) and TEM (JEOL JEM-100CX II, 100 kV). The structure using XRD (Rigaku Smartlab 9kW) and the chemical composition using WDX (Philips, XL30ESEM). Gas sensors were tested in a continuous flow (200 sccm) test chamber (280 cm<sup>3</sup>) comprised of a mass flow system (Bronkhorst hi-tech 7.03.241) and calibrated cylinders of hydrogen (H<sub>2</sub>, Praxair, 1000 ppm), carbon monoxide (CO, Praxair, 1000 ppm) and synthetic air (Carburros Metálicos, 99.99%) as described previously.[6] The sensor response was defined as  $R = R_a/R_{gas}$ , where  $R_a$  is the sensor resistance in air and  $R_{gas}$  the sensor resistance after 10 min of the analyte exposure. The response time ( $t_R$ ) was defined as the time required for the sensor to reach 90% of the sensor response, and the recovery time ( $t_{rec}$ ) as the time required to reach 10% of the initial baseline resistance after the analyte was purged.

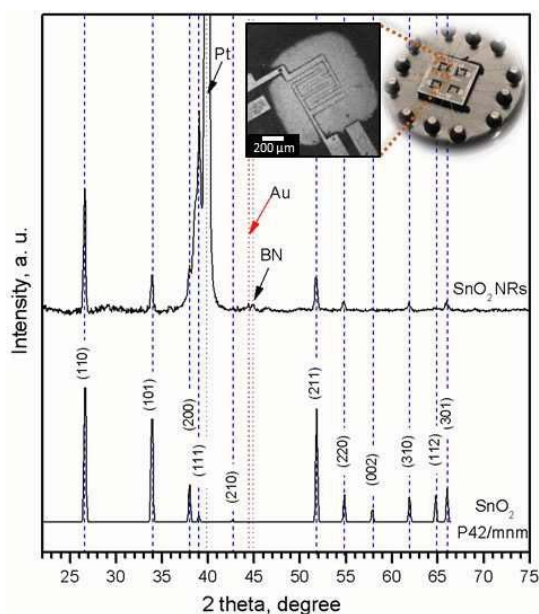


Fig. 1. XRD of a microsensors based on Au@SnO<sub>2</sub> NRs grown via AA-CVD. Diffraction peaks are indexed to a tetragonal phase (P42/mmm, ICCD card no. 41-1445) of tin oxide and face-centered cubic Au (Fm3m, ICCD card no. 4-0784). Platinum (Pt) and boron nitride (BN) diffraction peaks coming from the microsensors platform are also identified.

### 3. Results and discussion

XRD of the films composed of Au@SnO<sub>2</sub> and SnO<sub>2</sub> NRs indicated the presence of tetragonal SnO<sub>2</sub> (P42mm space group,  $a=4.7382$  Å,  $c=3.1871$  Å; ICCD card no. 411-1445) with a weak diffraction at 44.3 degrees in the Au@SnO<sub>2</sub> films corresponding to the (200) reflections of face-centered cubic Au (Fm3m space group,  $a=4.07860$  Å; ICCD card no. 04-0784) (**Fig. 1**). XPS of the films indicated a (0.9 at.%) 3.7 wt.% Au in the films with the characteristics of Au 4f core level spectra being in agreement with that reported for gold metal,[5] which suggests the gold NPs incorporated at the surface of the tin oxide NRs are in the metallic state.

SEM of the  $\mu$ MP showed films composed of non-aligned NRs, grown uniformly on the electrodes (**Fig. 2a** and **2b**). Similarly, TEM confirmed the formation of prism-like NRs terminated in a pyramidal cap and the incorporation of Au NPs (~35 nm) with spherical morphologies at the NR surface (**Fig. 2c** and **2d**), proving consistency with our previous observations for the co-deposition of tungsten oxide and gold *via* AA-CVD.[5] The non-functionalized NRs grown on the  $\mu$ MP *via* AA-CVD showed similar morphological, chemical and crystal structure for SnO<sub>2</sub>.

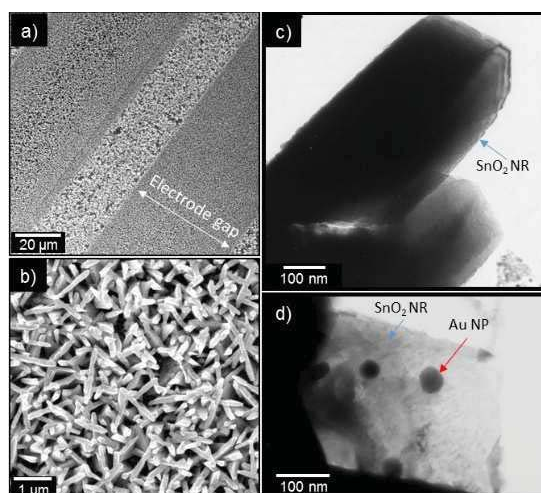


Fig. 2. Typical low (a) and high (b) magnifications SEM imaging of the SnO<sub>2</sub> and Au@SnO<sub>2</sub> NRs grown via AACVD on the  $\mu$ MP. TEM of a single SnO<sub>2</sub> (c) and Au@SnO<sub>2</sub> (d) NR.

Test of the samples towards H<sub>2</sub> and CO registered stable signal and very low drift of electrical resistance over the testing period, with the Au@SnO<sub>2</sub> sensors showing enhanced sensing characteristics compared to SnO<sub>2</sub> sensors, which included higher and faster response and lower-cross response (**Table 1** and **Fig. 3**). A comparison of these results with those recorded for similar systems synthesised *via* sol-gel in the literature[7] revealed nearly 7 times higher values for our Au@SnO<sub>2</sub> NRs, suggesting the AA-CVD method presented here allows for not only a direct integration with  $\mu$ MP, but also for an effective functionalization of SnO<sub>2</sub>.

Table 1. Sensor response and cross-response ( $\Delta R$ ) towards H<sub>2</sub> and CO for the SnO<sub>2</sub> and Au@SnO<sub>2</sub> sensors operating at 290 °C.

Analytes & cross-response	Response, $R_a/R_{gas}$	
	SnO <sub>2</sub>	Au@SnO <sub>2</sub>
250 ppm H <sub>2</sub>	3.3	35.4
500 ppm H <sub>2</sub>	3.8	41.1
250 ppm CO	1.1	1.6
500 ppm CO	1.2	1.9
$\Delta R_{500 \text{ ppm}} = (R_{H_2} - R_{CO})$	2.6	39.2

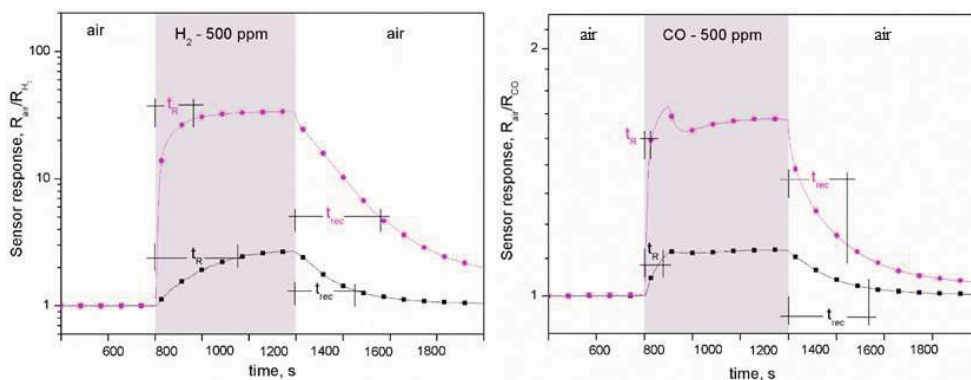


Fig. 3. Maximum sensor response recorded with the SnO<sub>2</sub> and Au@SnO<sub>2</sub> NRs towards 500 ppm of either H<sub>2</sub> or CO at 290 °C or 320 °C, respectively.

#### 4. Conclusion

Micromachined chemoresistive gas sensors based on SnO<sub>2</sub> and Au@SnO<sub>2</sub> NRs were developed using AA-CVD of SnCl<sub>4</sub>·5H<sub>2</sub>O at 620 °C, a much lower onset temperature compared to other CVD methods based on a VS mechanism, which typically requires temperatures exceeding 850 °C. The gas microsensors were validated towards H<sub>2</sub> and CO and show sensing properties that are in agreement with the literature, with notable enhancement of sensing properties for Au@SnO<sub>2</sub> NRs which showed 12-fold higher response with 6-fold faster response and improved selectivity to H<sub>2</sub> compared to the gas sensors based on intrinsic SnO<sub>2</sub> NRs.

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